

Transaction Information

Tool ID	U88V
Tool Status	Connected
Location	Burlington, USA
Wafer Size	200 mm
Fab Section	Thin Film
Tool Available Date	2023-09-01

General Product Information

Vendor Supplier	Jusung Engineering Co., LTD
Model	Eureka 2000
Vintage	2002
Serial No	2100
Asset Description	2 load ports
Software Version	XP GUI_2100 v2.2.3
CIM	NONE
Process	Tantalum Oxide (Ta2O5) & Alumina (Al2O3)

Hardware Configuration (Fab)

System Type	Description	Quantity	Status
Main System	Brooks Transfer Module and 2 Load Locks	1	OK
Handler System	Brooks Automation MX700 platform w/ 2 VCE6, TopLigner, Magnatran 7 with Leapfrog armset	1	OK
Factory Interface	SMIF	2	OK
Others			
Options System			

Hardware Configuration (Subfab / Auxilliary Units)

Description	Quantity	Status
LDS Cabinet, Jusung	1	OK
Heat Exchangers, FST Inc. FSTC-HD366AJ-H	1	OK
Heat Exchangers, Bay Voltex HRE-HT-0650-DC-G	1	OK
Ozone System, IN USA ODS-ALMO-2	1	OK
Mini Environment	1	OK
Pumps, Ebara A10S	4	OK
Pumps, Ebara AAS200WN	2	OK

Missing/Faulty Parts / Accesories List

Description	Quantity
PM4 (1 Al2O3 chamber), One of 3 solenoid banks	1
PM2 (1 Ta2O5 chamber), onboard LDS	1

Description	Quantity
heater controller (Anafaze CLS208)	
PM2 (1 Ta2O5 chamber), Controller (computer), associated software, and data gateway	1
PM2 (1 Ta2O5 chamber), Brake for the wafer up/down stepper motor	1
PM2 (1 Ta2O5 chamber), Wafer chuck/heater temp controller (Eurotherm 2704)	1
PM4 (1 Al2O3 chamber), Final valves	1
PM2 (1 Ta2O5 chamber), Fast valve/roughing valve assembly (custom)	1
PM4 (1 Al2O3 chamber), Wafer heater/chuck	1
PM2 (1 Ta2O5 chamber), Wafer up/down stepper controller (Parker GT6)	1
PM4 (1 Al2O3 chamber), Foreline convectron guage	1
PM4 (1 Al2O3 chamber), Chamber pump	1
PM4 (1 Al2O3 chamber), Lower foreline components	1
PM4 (1 Al2O3 chamber), Slot valve housing and	1

Description	Quantity
actuator	
PM4 (1 Al2O3 chamber), Chamber manometer	1
PM4 (1 Al2O3 chamber), Chuck heater temp controller (Eurotherm 2704)	1
PM4 (1 Al2O3 chamber), All gasbox and LDS (TMA) components	1
PM2 (1 Ta2O5 chamber), Chamber pump	1
PM4 (1 Al2O3 chamber), Controller (computer), associated software, and data gateway	1
PM2 (1 Ta2O5 chamber), Watlow anafaze PPC TB50 board	1

Tool Pictures

General	none
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Main Systems (SMIF / Handlers / Chambers)



Auxiliary Systems



Manufacture Serial

NONE

Manufacturer Tag

SYSTEM : LP CVD Process Module 5

MODEL : EUREKA2000

Serial No. : 2100

Made in Korea

JUSUNG ENGINEERING CO.,LTD

Additional Tool Data Files